

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE**INFORMATION DISCLOSURE  
STATEMENT**Docket Number  
**10191/1466**Application Number  
**To Be Assigned**Filing Date  
**Herewith**Examiner  
**To Be Assigned**Art Unit  
**To Be Assigned**Invention Title  
**METHOD FOR PROCESSING SILICON  
BY ETCHING PROCESSES**Inventor(s)  
**Volker BECKER; Franz LAERMER; and  
Andrea SCHILP**

Address to:  
Assistant Commissioner for Patents  
Washington, D.C. 20231

1. In accordance with the duty of disclosure under 37 C.F.R. § 1.56 and in conformance with the procedures of 37 C.F.R. §§ 1.97 and 1.98 and M.P.E.P. § 609, attorneys for Applicants hereby bring the following references to the attention of the Examiner. The references are listed on the attached modified PTO form 1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.
2. A copy of each patent, publication or other information listed on the modified PTO form 1449 is enclosed, except as otherwise indicated on the modified PTO form 1449.

Dated:

June 15, 2000

By:

RL Mayer

Richard L. Mayer (Reg. No. 22,490)

KENYON & KENYON  
One Broadway  
New York, N.Y. 10004  
(212) 425-7200 (telephone)  
(212) 425-5288 (facsimile)